

## Refine Search

10/829,382

### Search Results -

Terms	Documents
L6 and (cleaning near4 chamber)	3

Database:

US Pre-Grant Publication Full-Text Database  
 US Patents Full-Text Database  
 US OCR Full-Text Database  
 EPO Abstracts Database  
 JPO Abstracts Database  
 Derwent World Patents Index  
 IBM Technical Disclosure Bulletins

Search:

L7

Refine Search

Recall Text

Clear

Interrupt

### Search History

 DATE: Wednesday, April 13, 2005    [Printable Copy](#)    [Create Case](#)
**Set Name Query**  
 side by side

**Hit Count Set Name**  
 result set

DB=USPT; PLUR=YES; OP=ADJ

<u>L7</u>	L6 and (cleaning near4 chamber)	3	<u>L7</u>
<u>L6</u>	L4 and halogen	10	<u>L6</u>
<u>L5</u>	L4 and ((react or reacting) near3 halogen)	0	<u>L5</u>
<u>L4</u>	L3 and plasma	47	<u>L4</u>
<u>L3</u>	L2 and (second near2 temperature)	78	<u>L3</u>
<u>L2</u>	L1 and (decreasing near6 temperature)	372	<u>L2</u>
<u>L1</u>	(film near8 chamber)	21483	<u>L1</u>

END OF SEARCH HISTORY

## Hit List

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Search Results - Record(s) 1 through 3 of 3 returned.

☐ 1. Document ID: US 6495054 B1

L7: Entry 1 of 3

File: USPT

Dec 17, 2002

US-PAT-NO: 6495054

DOCUMENT-IDENTIFIER: US 6495054 B1

TITLE: Etching method and cleaning method of chemical vapor growth apparatus

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	RMC	Draw D
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☐ 2. Document ID: US 5994678 A

L7: Entry 2 of 3

File: USPT

Nov 30, 1999

US-PAT-NO: 5994678

DOCUMENT-IDENTIFIER: US 5994678 A

TITLE: Apparatus for ceramic pedestal and metal shaft assembly

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	RMC	Draw D
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☐ 3. Document ID: US 5983906 A

L7: Entry 3 of 3

File: USPT

Nov 16, 1999

US-PAT-NO: 5983906

DOCUMENT-IDENTIFIER: US 5983906 A

TITLE: Methods and apparatus for a cleaning process in a high temperature, corrosive, plasma environment

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	RMC	Draw D
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Clear	Generate Collection	Print	Fwd Refs	Bkwd Refs	Generate OACS
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Terms	Documents
L6 and (cleaning near4 chamber)	3

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Search Results - Record(s) 1 through 10 of 10 returned.

☐ 1. Document ID: US 6534401 B2

L6: Entry 1 of 10

File: USPT

Mar 18, 2003

US-PAT-NO: 6534401

DOCUMENT-IDENTIFIER: US 6534401 B2

TITLE: Method for selectively oxidizing a silicon/metal composite film stack

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	FIGS	Draw D
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☐ 2. Document ID: US 6495054 B1

L6: Entry 2 of 10

File: USPT

Dec 17, 2002

US-PAT-NO: 6495054

DOCUMENT-IDENTIFIER: US 6495054 B1

TITLE: Etching method and cleaning method of chemical vapor growth apparatus

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	FIGS	Draw D
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☐ 3. Document ID: US 6403497 B1

L6: Entry 3 of 10

File: USPT

Jun 11, 2002

US-PAT-NO: 6403497

DOCUMENT-IDENTIFIER: US 6403497 B1

TITLE: Method of manufacturing semiconductor device by two stage heating of deposited noncrystalline semiconductor

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	FIGS	Draw D
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☐ 4. Document ID: US 6235563 B1

L6: Entry 4 of 10

File: USPT

May 22, 2001

US-PAT-NO: 6235563

DOCUMENT-IDENTIFIER: US 6235563 B1

TITLE: Semiconductor device and method of manufacturing the same

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KWIC	Draw D
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☐ 5. Document ID: US 5994678 A

L6: Entry 5 of 10

File: USPT

Nov 30, 1999

US-PAT-NO: 5994678

DOCUMENT-IDENTIFIER: US 5994678 A

TITLE: Apparatus for ceramic pedestal and metal shaft assembly

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KWIC	Draw D
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☐ 6. Document ID: US 5983906 A

L6: Entry 6 of 10

File: USPT

Nov 16, 1999

US-PAT-NO: 5983906

DOCUMENT-IDENTIFIER: US 5983906 A

TITLE: Methods and apparatus for a cleaning process in a high temperature, corrosive, plasma environment

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KWIC	Draw D
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☐ 7. Document ID: US 5837032 A

L6: Entry 7 of 10

File: USPT

Nov 17, 1998

US-PAT-NO: 5837032

DOCUMENT-IDENTIFIER: US 5837032 A

TITLE: Gas separations utilizing glassy polymer membranes at sub-ambient temperatures

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KWIC	Draw D
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☐ 8. Document ID: US 5705329 A

L6: Entry 8 of 10

File: USPT

Jan 6, 1998

US-PAT-NO: 5705329

DOCUMENT-IDENTIFIER: US 5705329 A

TITLE: Silver halide photographic light-sensitive material

Full	Title	Citation	Front	Review	Classification	Date	Reference	Claims	KWIC	Draw D
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☐ 9. Document ID: US 5679133 A

L6: Entry 9 of 10

File: USPT

Oct 21, 1997

US-PAT-NO: 5679133

DOCUMENT-IDENTIFIER: US 5679133 A

TITLE: Gas separations utilizing glassy polymer membranes at sub-ambient temperatures

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KWD	Draw D
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☐ 10. Document ID: US 5352272 A

L6: Entry 10 of 10

File: USPT

Oct 4, 1994

US-PAT-NO: 5352272

DOCUMENT-IDENTIFIER: US 5352272 A

TITLE: Gas separations utilizing glassy polymer membranes at sub-ambient temperatures

Full	Title	Citation	Front	Review	Classification	Date	Reference			Claims	KWD	Draw D
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Terms	Documents
L4 and halogen	10

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